

What is claimed is:

1. A substrate testing device for testing a substrate by scanning of an electron beam across the substrate, comprising:

5 a testing unit for acquiring a tested result of the substrate by the scanning of the electron beam;

an alignment mark detecting unit for optically detecting an alignment mark on the substrate;

a substrate position calculating unit for calculating a substrate position within said substrate testing device from

10 a position of said alignment mark; and

15 a position aligning unit for aligning a position of tested result with the calculated substrate position, said position aligning unit allocating the tested result to the substrate position.

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2. The substrate testing device according to claim 1, wherein said position aligning unit aligns a defect result obtained by a defect test based on the tested result with the substrate position.

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3. The substrate testing device according to claim 1, wherein said alignment mark detecting unit comprises an optical microscope or a CCD camera for picking up an image of the alignment mark on the substrate.

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4. The substrate testing device according to claim 2, wherein said alignment mark detecting unit comprises an optical microscope or a CCD camera for picking up an image of the alignment mark on the substrate.

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5. A substrate testing method for testing a substrate by scanning of an electron beam across the substrate within a substrate testing device, comprising:

acquiring a tested result of the substrate by the scanning  
10 of the electron beam;

optically detecting an alignment mark on the substrate;  
calculating a substrate position within the substrate  
testing device from a position of the alignment mark;

aligning a position of tested result with the calculated  
15 substrate position; and

allocating the tested result to the substrate position.

6. The substrate testing method according to claim 5, wherein said position aligning step includes aligning a defect  
20 result obtained by a defect test based on the tested result with the substrate position.